



Electrothermal and Electrostatic Actuators for Assembly, Robotics and Micromanipulation Applications

Guest Editors:

Dr. Rodica Voicu

IMT Bucharest Modeling,
Simulation and CAD Laboratory,
National Institute for Research
and Development in
Microtechnologies—IMT
Bucharest, 126A Erou Iancu
Nicolae Street, 077190 Bucharest,
Romania

Dr. Jian LU

Device Technology Research
Institute, National Institute of
Advanced Industrial Science and
Technology (AIST), Namiki 1-2-1,
Tsukuba, Ibaraki, Japan

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Message from the Guest Editors

In this Special Issue, we aim to highlight some of the recent developments and achievements in electrothermal and electrostatic actuators, their integration in different MEMS/MOEMS/NEMS devices and sensors, and structural advanced materials used for fabrication and different applications, such as micromanipulation techniques. The realization of actuators with an out-of-plane motion is still a challenging task in the domain of micro-electro-mechanical (optical) systems (MEMS/ MOEMS). The designed micro-actuators can be used in a variety of applications, such as in bio-medicine, micro-robotics, for grippers actuation, in assembling for positioning, and the manipulation of micro-elements (like mirrors, lenses, or bio-elements) in electronics as for switches or RF applications or mirrors.

We invite the submission of research papers and reviews that focus on tethered or untethered actuators used for devices with applications in the manipulation, fabrication, or characterization of different structural materials used. Topics of particular interest include but are not limited to, modeling and simulation, design, fabrication, as well as characterization at small scales and experiments.

